

Application Data Sheet

Application Information

Application number::

Filing Date::

Application Type::

Regular

Subject Matter::

Utility

Title ::

BEAM IRRADIATION
APPARATUS, BEAM
IRRADIATION METHOD,
AND METHOD FOR
MANUFACTURING THIN
FILM TRANSISTOR

Attorney Docket Number::

0756-7285

Total Drawing Sheets::

8

Small Entity?::

No

Applicant Information

Applicant Authority Type::

Inventor

Primary Citizenship Country::

Japan

Given Name::

Koichiro

Middle Name::

Family Name::

TANAKA

Name Suffix::

City of Residence::

Atsugi

State or Province of Residence::

Kanagawa

Country of Residence::

Japan

Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
City of mailing address:: Atsugi-shi
State or Province of mailing address:: Kanagawa-ken
Country of mailing address:: Japan
Postal or Zip Code of mailing address:: 243-0036

Correspondence Information

Correspondence Customer Number :: 31780
E-Mail address:: erobinson@riplo.com

Representative Information

Representative Customer Number:: 31780

Domestic Priority Information

| Application :: | Continuity Type:: | Parent Application:: | Parent Filing Date:: |
|----------------|-------------------|----------------------|----------------------|
| | | | |
| | | | |
| | | | |

Foreign Priority Information

| Country:: | Application number:: | Filing Date:: | Priority Claimed:: |
|-----------|----------------------|---------------|--------------------|
| Japan | 2003-116408 | 04/21/2003 | Yes |
| | | | |

Assignee Information

| | |
|---|--|
| Assignee name:: | Semiconductor Energy Laboratory Co., Ltd. |
| Street of mailing address:: | 398, Hase |
| City of mailing address:: | Atsugi-shi |
| State or Province of mailing address:: | Kanagawa-ken |
| Country of mailing address:: | Japan |
| Postal or Zip Code of mailing address:: | 243-0036 |